



**Table for Facility Charges**

Equipment(s)		Facility Code	Facility	Charges (Rs.) per sample per measurement*						Contact Person:	
				User Category							
				External		HNBGU campuses					
				Users from Industries/ Private users	Edu. Inst./ Govt. organization	Research Scholar/P.I./Co-P.I. Of a research project	Ph.D. scholar with fellowship	Student / Research Scholar without fellowship	Teachers/ Research staff		
				A	B	C	D	E	F		
<b>X-ray Diffractometer (PANalytical)</b>	1	XRD-PS	XRD of Powder sample	1000/-	500/-	400/-	250/-	100/-	200/-	<b>1. Mr. G. S. Kathait</b> Email- gambhir11186@gmail.com & gs.kathait@hnbgu.ac.in Mob. No. - 09897108774 <b>2. Mr. Prashant Thapliyal</b> Email- pra.thapli1986@gmail.com & p.thapliyal@hnbgu.ac.in Mob. No.- 07830506095	
	2	XRD-TF	XRD of Thin film sample	1500/-	750/-	600/-	450/-	150/-	350/-		
	3	XRD-HT	XRD at High Temp. (upto 500 <sup>0</sup> C) (Extra charge per 2θ scan)	1200/-	600/-	500/-	300/-	150/-	250/-		
	4	XRD-RM	X- ray Reflectivity measurment in Thin Film	2000/-	800/-	500/-	400/-	200/-	300/-		
	5	XRD-SM	XRD Search match for identification with PDF 2012 (Extra charge per 2θ scan)	500/-	250/-	200/-	150/-	50/-	100/-		
<b>Scanning Electron Microscope (SEM) with EDAX</b>	1	<b>High Vacuum Mode</b>									<b>Mr. Prashant Thapliyal</b> Email - pra.thapli1986@gmail.com & p.thapliyal@hnbgu.ac.in Mob. No.- 07830506095
		SEM-HV-TF	SEM Image (upto 3-4 nm resolution)	750/-	400/-	300/-	175/-	80/-	125/-		
		SEM-HV-LF	SEM Image (upto 1-2 nm resolution)	1500/-	800/-	600/-	350/-	160/-	250/-		
		SEM-D	Sample drying upto 200 <sup>0</sup> C for 2 hrs (if required)	75/-	50/-	40/-	25/-	10/-	35/-		
	2	<b>Low Vacuum Mode</b>									
		SEM-LV-TF	SEM Image (upto 3-4 nm resolution)	1500/-	800/-	600/-	350/-	160/-	250/-		
		SEM-LV-LF	SEM Image (upto 1-2 nm resolution)	3000/-	1600/-	1200/-	750/-	320/-	500/-		
	3	SEM-C	Coating with Au-Pd target (for non-conducting sample)	200/-	100/-	75/-	50/-	15/-	60/-		
4	SEM-EDX	Elements identification and quantification with EDAX (Charges per selected spot)	500/-	300/-	200/-	125/-	40/-	100/-			
<b>ICP-MS Spectroscopy with Laser Ablation system (Perkin Elmer)</b>	1	ICPMS-SE	Standardization and Estimation per element	1500/-	750/-	600/-	450/-	150/-	350/-	<b>1. Mr. Vishal Rohilla</b> Email- mail.vishal.pd@gmail.com & vishal.rohilla@hnbgu.ac.in Mob. No. - 09411301658 <b>2. Mr. Don Viswas</b> Email- donusic06@gmail.com & d.biswas@hnbgu.ac.in Mob. No. - 07579021861	
	2	ICPMS-SS	Same element of subsequent sample	500/-	250/-	200/-	150/-	50/-	100/-		
	3	ICPMS-P&C	Sample preparation and consumables	500/-	250/-	200/-	150/-	50/-	100/-		

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<b>Ellipsometer</b>	1	<b>EM-T&amp;R</b>	<i>Thickness and refractive index of thin films</i>	1100/-	550/-	450/-	300/-	100/-	150/-
<b>PE Loop tracer with Piezo-electric measurments</b>	1	<b>PE-BS</b>	<i>PE Loop of Bulk sample</i>	1800/-	500/-	400/-	300/-	100/-	150/-
	2	<b>PE-BS-HT</b>	<i>PE Loop of Bulk sample, upto 300<sup>0</sup> C (per scan, at one temp.)</i>	2500/-	700/-	500/-	400/-	150/-	200/-
	3	<b>PE-TF</b>	<i>PE Loop of Thin film sample</i>	1800/-	500/-	400/-	300/-	100/-	150/-
	4	<b>PE-PC-B</b>	<i>Piezoelectric coefficient of Bulk sample</i>	1800/-	500/-	400/-	300/-	100/-	150/-
	5	<b>PE-CM-RT</b>	<i>Capacitance measurement, upto 1 MHz, at RT</i>	500/-	300/-	250/-	150/-	50/-	75/-
	6	<b>PE-CM-HT</b>	<i>Capacitance measurement, upto 1 MHz, at RT &lt;T≤ 300<sup>0</sup> C, at a step of 5<sup>0</sup> C (extra charges )</i>	800/-	500/-	300/-	200/-	75/-	100/-
<b>RCL meter (upto 1 MHz)</b>	1	<b>Bulk sample - Capacitance vs. frquency.</b>							
		<b>RCL-RT</b>	<i>At room temp.</i>	500/-	300/-	250/-	150/-	50/-	75/-
		<b>RCL--HT</b>	<i>At different temp., RT&lt;T≤ 500<sup>0</sup> C, at a step of 5<sup>0</sup> C (extra charges than RT)</i>	1000/-	500/-	300/-	100/-	75/-	100/-
		<b>RCL--DC</b>	<i>with per DC bias, upto 40V (extra)</i>	1000/-	600/-	500/-	300/-	100/-	150/-
	2	<b>Thin Film Sample - Capacitance vs. frquency</b>							
		<b>RCL-CF</b>	<i>At RT</i>	1100/-	550/-	450/-	300/-	100/-	200/-
<b>RCL-CV</b>		<i>Capacitance vs. Voltage, at RT, and 1MHz</i>	1100/-	550/-	450/-	300/-	100/-	200/-	
<b>Source Meter</b>	1	<b>SM-IV</b>	<i>I-V (upto 10 V, for thin films; and 200 V, for bulk,</i>	1100/-	550/-	450/-	300/-	100/-	200/-
<b>Spectrophotometer (Visible + UV)</b>	1	<b>SP-TR/W</b>	<i>T%/R %/ Abs% vs. Wavelength</i>	1000/-	500/-	400/-	250/-	100/-	200/-
	2	<b>SP-DR/W</b>	<i>Diffused reflectance vs. Wavelength</i>	1500/-	800/-	600/-	350/-	160/-	250/-
<b>Muffel Furnance</b>	1	<b>MF-1150</b>	<i>RT to 1150<sup>0</sup> C (per hr. charges)</i>	500/-	200/-	150/-	100/-	50/-	75/-
	2	<b>MF-1750</b>	<i>RT to 1400<sup>0</sup> C (per hr. charges)</i>	1000/-	400/-	300/-	200/-	100/-	150/-
<b>Oven</b>	1	<b>OV-300</b>	<i>Drying upto 300<sup>0</sup> C, per hr.</i>	250/-	100/-	75/-	50/-	25/-	45/-
<b>Double Distilled water Plant</b>	1	<b>DW</b>	<i>Distilled Water</i>	20/-	15/-	10/-	10/-	10/-	10/-
<b>Liquid Nitrogen Plant</b>	1	<b>LN2</b>	<i>LN2 [B.P. - (-)196<sup>0</sup> C]</i>	50/-	30/-	20/-	20/-	20/-	20/-